

Title (en)

Method and device for generating plasma

Title (de)

Verfahren und Einrichtung zum Erzeugen von Plasma

Title (fr)

Procédé et dispositif pour la génération de plasma

Publication

EP 0963140 B1 20040908 (DE)

Application

EP 99890141 A 19990430

Priority

AT 28598 U 19980504

Abstract (en)

[origin: EP0963140A2] The method involves igniting a light arc between an anode and a cathode and using it to ionise a gas or vapour. The light arc is powered by voltage pulses, whereby the voltage applied to the anode-cathode path falls below the ignition voltage during the pauses between pulses so that the light arc is quenched in the pauses. An Independent claim is also included for an arrangement for implementing the method.

IPC 1-7

H05H 1/36

IPC 8 full level

H05H 1/36 (2006.01)

CPC (source: EP US)

H05H 1/36 (2013.01 - EP US)

Citation (examination)

- US 5421312 A 19950606 - DAWSON JOSEPH G [GB]
- DE 4008405 C1 19910711
- US 3447322 A 19690603 - MASTRUP FRITHJOF N
- US 4974487 A 19901204 - GOLDSTEIN YESHAYAHU S A [US], et al
- NEUBERT G. ET AL: "Grundlagen der Schweißtechnik, Energiequellen und Einrichtungen", 1988, VEB VERLAG TECHNIK, BERLIN

Cited by

DE102009015510B4; DE102010003351A1

Designated contracting state (EPC)

CH DE ES FR GB IT LI NL SE

DOCDB simple family (publication)

EP 0963140 A2 19991208; EP 0963140 A3 20020515; EP 0963140 B1 20040908; AT 3549 U1 20000425; CA 2270072 A1 19991104; CA 2270072 C 20071113; CZ 159799 A3 20000517; CZ 295951 B6 20051214; DE 59910426 D1 20041014; HU 9900992 D0 19990628; HU P9900992 A2 20001128; HU P9900992 A3 20021228; US 6225743 B1 20010501

DOCDB simple family (application)

EP 99890141 A 19990430; AT 28598 U 19980504; CA 2270072 A 19990427; CZ 159799 A 19990504; DE 59910426 T 19990430; HU P9900992 A 19990408; US 29671899 A 19990422